

# Identification of Suitable Substrate for Assessing Personal Exposure to Nanoparticles by Transmission Electron Microscopy

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#### Background

Nanoparticles (<100 nm diameter) are shown to be particularly toxic when inhaled. Adverse health effects are more strongly related to particle number or surface area than mass concentration. Sampling methods to assess personal exposure to number or surface area concentration are unavailable.

Sample analysis by transmission electron microscopy (TEM) would allow distinction between engineered and incidental nanoparticles. This ability may be critical in assessing workplace inhalation hazards.

An appropriate deposition surface compatible with TEM analysis is needed for incorporation into novel personal samplers that our group and others are developing.

### Objective

Identify an appropriate deposition surface for analysis of nanoparticles by TEM

#### Methods

- Collect particles on various substrates
- Image particles byTEM
- Size particles with ImageJ software
- Compare size distribution to real time equipment output (SMPS)

### Implications

- TEM analysis allows
- 1) sizing and counting of nanoparticles
- 2) distinction between engineered and incidental nanoparticles
- Distinction is critical to assess workplace health effects
- Deposition substrate is crucial for development of passive and filter samplers
- •Novel sampling methods will help assess personal exposure to number or surface area concentration



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## Results

Expected an diameter	Measured mean diameter	Standard Deviation	Pros and Cons
nm – 2 um	Not Calculated	Not Calculated	Background noise makes it difficult to clearly size particles using computer software
50 nm	52.32 nm	4.29 nm	Greater particle collection than tube sampler Holes useful to increase deposition with active filter sampling Large holes in background pose problem for sizing software
50 nm	53.21 nm	7.3 nm	Lower collection because no flow through film Clean background Sizing consistent with real time equipment
0 ± 4 nm	33.29 nm	3.05 nm	Clean background Optimal particle/background contrast

#### **Future Research**

useful to evaluate substrates

- Perform rigorous test of deposition substrates
- Incorporate substrate optimal for imaging into tube sampling method for nanoparticles
- Use method to distinguish airborne engineered nanomaterials from incidental nanoparticles

#### Funded by NIOSH KO1 OH009255 grant